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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Hachishiro IIZUKA

SERIAL NO.: NEW U.S. PCT APPLICATION

FILED: HEREWITH

INTERNATIONAL APPLICATION NO.: PCT/JP04/10895

INTERNATIONAL FILING DATE: July 23, 2004

FOR: GAS REACTION SYSTEM AND SEMICONDUCTOR PROCESSING APPARATUS

**REQUEST FOR PRIORITY UNDER 35 U.S.C. 119**  
**AND THE INTERNATIONAL CONVENTION**

Commissioner for Patents  
Alexandria, Virginia 22313

Sir:

In the matter of the above-identified application for patent, notice is hereby given that the applicant claims as priority:

**COUNTRY**  
Japan

**APPLICATION NO**  
2003-279970

**DAY/MONTH/YEAR**  
25 July 2003

Certified copies of the corresponding Convention application(s) were submitted to the International Bureau in PCT Application No. PCT/JP04/10895. Receipt of the certified copy(s) by the International Bureau in a timely manner under PCT Rule 17.1(a) has been acknowledged as evidenced by the attached PCT/IB/304.

Respectfully submitted,  
OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.



Steven P. Weihrouch  
Attorney of Record  
Registration No. 32,829  
Surinder Sachar  
Registration No. 34,423

Customer Number

**22850**

(703) 413-3000  
Fax No. (703) 413-2220  
(OSMMN 08/03)